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Substitute for form 1449A/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)		Complete if Known	
		Application Number	12/643,556
		Filing Date	8/18/2003
		First Named Inventor	Jesse Wolfe et al
		Group Art Unit	1753
		Examiner Name	VerSteeg
Sheet 1 of 2	Attorney Docket Number	IL-11072	

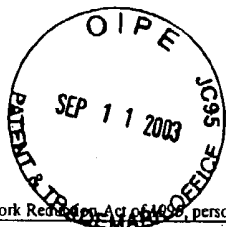
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Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
SAV		5798027		Lefebvre et al	8/25/1998	204 192 26
SHV		5702573		Biberger et al	12/30/1997	204 192 12
SHV		5225057		Lefebvre et al	7/6/1993	204 192 13
SHV		5346600		Nieh et al	7/13/1994	204 192 3
SHV		5618388		Seeser et al	4/8/1997	204 192 12
SHV		5851365		Michael Scobey	12/22/1998	204 192 12

FOREIGN PATENT DOCUMENTS						
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		Office ³	Number	Kind Code ⁵ (if known)		

Examiner Signature		Date Considered	January 10, 2005
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¹ Unique citation designation number. ² See attached Kinds of U.S. Patent Documents. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶ Applicant is to place a check mark here if English language Translation is attached.
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		Group Art Unit	1753
		Examiner Name	VerSteege
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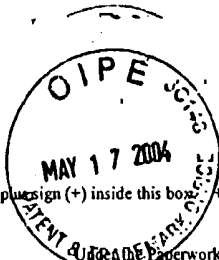
OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.		
SHV		Broughton J.N. et al	Long Throw Sputter Deposition of Titanium at Low Pressures	1995 VMIC Conference June 27-29 1995 ISMIC - 104/95/0201 (pages 201-203)
SHV		Rossnagel S. M. et al	Sputter Deposition for Semiconductor Manufacturing	IBM Journal of Research and Development Volume 43, 1/2 1999 Plasma Processing (pages 1-14)
SHV		Nam-Woong Paik et al	The characterization of a New Plasma-Magnetron-Sputter-Type Negative Ion Source	Presented to the Journal of Applied Physics - Pre-print of a journal (4 pages)
SHV		Bradley J.W. et al	Time-Resolved Langmuir Probe Measurements at the Substrate Position in a Pulsed Mid-frequency DC Magnetron Plasma	Elsevier Surface & Coatings Technology 135 2001 (pages 221-228)
SHV		L.B. Jonsson et al	Frequency response in pulsed DC reactive sputtering processes	Elsevier Thin Solid Films 365 (2000) 43-48
SHV		A.A. Mayo et al	Across-wafer nonuniformity of long throw sputter deposition	American Vacuum Society J. Vac Sci Technol. B 15(5) Sep/Oct 1997
SHV		A. Belkind et al	Electrical Dynamics of Pulsed Plasmas	1998 Society of Vacuum Coaters 505 pages 321-326
SHV		D. Carter et al	Parameter Optimization in Pulsed DC Reactive Sputter Deposition of Aluminum Oxide	2002 Society of Vacuum Coaters 45 th Annual Technical Conference Proceedings pages 570-577
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		Filing Date	August 18, 2003
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		Group Art Unit	1753
		Examiner Name	Ver Steeg
Sheet 1 of 1	Attorney Docket Number	IL-11072	

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		Office ³	Number	Kind Code ⁴ (if known)				
SHV		WO	01/98553	A1	Vladimir, Kouznetsov	12-27-2001	class 1 sbclass 14/35	

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